

Application No. 09/955,722
SD-6436.1 S-97675

AMENDMENT TO THE SPECIFICATION

- Please replace the paragraph starting at page 13, line 27 with the following:

Fig. 2B shows a schematic cross-section view of a second example, according to the present invention, that is similar to Fig. 2A, after an optional anti-stiction coating 26 has been applied to the released MEMS elements. Anti-stiction coating 26 in Fig. 2B is an example of a class of performance-enhancing and/or proprietary films that can be applied to released MEMS elements 24. A schematic MEMS device 40 is shown, having MEMS elements 24 comprising two polysilicon gears 42, 44 and a linkage bar 46. Examples of performance-enhancing films include anti-stiction films, adhesion-inhibitors, lubricants (e.g. perfluoropolyether, hexamethyldisilazane, or perfluorodecanoic carboxylic acid), and nitrided-surfaces that reduce friction between moving (e.g. polysilicon) surfaces. In U.S. Patent 5,766,367, "Method for Preventing Micromechanical Structures from Adhering to Another Object", Smith, et al. discloses the formation of an adhesion-inhibiting hydrophilic coating by immersing the MEMS components in a solvent containing hexamethyldisilazane. U.S. Patent 5,766,367 is herein incorporated by reference in its entirety. Also, vapor-deposited, self-assembling monolayer (SAM) lubricants, such as perfluorodecanoic carboxylic acid, can be used. Finally, some degree of humidity can also help to increase lubricity.